

Interview Summary

Application No.

09/938,611

Applicant(s)

FUNAYAMA ET AL. #16

Examiner

Tianjie Chen

Art Unit

2652

All participants (applicant, applicant's representative, PTO personnel):

(1) Tianjie Chen (Primary Examiner, PTO).

(3) _____

(2) Remus F. Fetea (Representative).

(4) _____

Date of Interview: 19 February 2004.

Type: a) ☐ Telephonic b) ☐ Video Conference

c) ☒ Personal [copy given to: 1) ☐ applicant 2) ☒ applicant's representative]

Exhibit shown or demonstration conducted: d) ☐ Yes e) ☒ No.

If Yes, brief description: _____

Claim(s) discussed: 1.

Identification of prior art discussed: Hayashi et al (US 6,490,139).

Agreement with respect to the claims f) ☐ was reached. g) ☐ was not reached. h) ☒ N/A.

Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: After discussion, Representative proposes to rephrase the language to better define the relationship among the insulation layer, yokes and MR element. Examiner's position is: if it has been clearly defined the Hayashi et al's reference will be overcome. As an Official amendment is submitted, Examiner will do further search to determine the patentability.

(A fuller description, if necessary, and a copy of the amendments which the examiner agreed would render the claims allowable, if available, must be attached. Also, where no copy of the amendments that would render the claims allowable is available, a summary thereof must be attached.)

THE FORMAL WRITTEN REPLY TO THE LAST OFFICE ACTION MUST INCLUDE THE SUBSTANCE OF THE INTERVIEW. (See MPEP Section 713.04). If a reply to the last Office action has already been filed, APPLICANT IS GIVEN ONE MONTH FROM THIS INTERVIEW DATE, OR THE MAILING DATE OF THIS INTERVIEW SUMMARY FORM, WHICHEVER IS LATER, TO FILE A STATEMENT OF THE SUBSTANCE OF THE INTERVIEW. See Summary of Record of Interview requirements on reverse side or on attached sheet.

Examiner Note: You must sign this form unless it is an Attachment to a signed Office action.

Chen Tianjie
02/19/04
Examiner's signature, if required


**BEFORE THE OFFICE OF ENROLLMENT AND DISCIPLINE
UNITED STATE PATENT AND TRADEMARK OFFICE**

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Expires: April 30, 2004



Harry J. Moatz
Director of Enrollment and Discipline